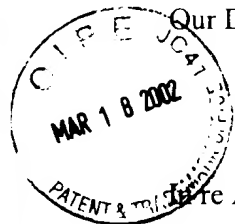


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Our Docket No: 42390P10058

Patent

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Re Application of:

Han-Ming Wu et al.

Examiner: Nguyen, Hung

Serial No: 09/752,938

Art Unit: 2851

Filed: December 29, 2000

For: Purging Gas from a Photolithography )  
Enclosure Between a Mask Protective )  
Device and a Pattern Mask )

RESPONSE TO OFFICE ACTION

Box Non Fee Amendment  
Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

In response to the Office Action mailed February 25, 2002 the Applicants respectfully request the Examiner to enter the following amendments and to consider the following remarks.

FIRST CLASS CERTIFICATE OF MAILING

I hereby certify that I am causing the above-referenced correspondence to be deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and that this paper or fee has been addressed to the Assistant Commissioner for Patents, Washington, D. C. 20231

March 8, 2002

Date of Deposit

Krista Mathieson

Name of Person Mailing Correspondence

*Krista Mathieson*

Signature

March 8, 2002

Date

Docket No.: 42390P10058  
Application No.: 09/752,938